

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re the Divisional Application of:

Shinji MIZUTANI

Serial No.: Div. of 09/476,208

Group Art Unit: 1756 (Expected)

Filed: August 16, 2001

Examiner: S. Rosasco (Expected)

For: **MICRO DEVICES MANUFACTURING METHOD
AND APPARATUS THEREFORE**

PRELIMINARY AMENDMENT

Commissioner of Patents
Washington, D.C. 20231

Date: August 16, 2001

Sir:

This is a Preliminary Amendment for the above-captioned Divisional application, concurrently filed herewith. Please amend the above-captioned Divisional application as follows:

IN THE SPECIFICATION:

Please replace the paragraph beginning at line 12, page 4, with the following rewritten paragraph:

A polishing surface plate 122 having a polishing pad 123 is disposed at a position that faces with the pattern formation surface 124a of the wafer 124 on the suction table 125. The polishing pad 123 rocks or oscillates in the same direction as the movement of a rocking table 121, since the polishing surface plate 122 is held by the rocking table 121.

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